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PATENT & TRADEMARK OFFICE

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Daniel Alvarez, Jr. and Jeffrey J. Spiegelman

Application No.: 10/683,904 Group Art Unit: 1746

Filed: October 10, 2003 Examiner: Bibi Sharidan Carrillo

Confirmation No.: 3090

Title: METHOD FOR THE REMOVAL OF AIRBORNE MOLECULAR CONTAMINANTS
USING WATER GAS MIXTURES

CERTIFICATE OF MAILING OR TRANSMISSION	
I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, or is being facsimile transmitted to the United States Patent and Trademark Office on:	
11-22-04	<i>Denise Canedo</i>
Date	Signature
<i>Denise Canedo</i>	
Typed or printed name of person signing certificate	

INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This Information Disclosure Statement is submitted:

☐ under 37 CFR 1.129(a), or

(First/Second submission after Final Rejection)

☐ under 37 CFR 1.97(b), or

(Within any one of the following time periods: three months of filing national application (other than a CPA) or date of entry of the national stage in an international application; or before the mailing date of a first office action on the merits in a non-provisional application, including a CPA, or a Request for Continued Examination).

☒ under 37 CFR 1.97(c) together with either:

☐ a Statement under 37 CFR 1.97(e), as checked below, or

☒ a \$180.00 fee under 37 CFR 1.17(p), or

(After the 37 CFR 1.97(b) time period, but before final action or notice of allowance, whichever occurs first)

☐ under 37 CFR 1.97(d) together with:

☐ a Statement under 37 CFR 1.97(e), as checked below, and

☐ a \$180.00 fee under 37 CFR 1.17(p), or

(Filed after final action or notice of allowance, whichever occurs first, but on or before payment of the issue fee)

☐ under 37 CFR 1.97(i):

Applicant requests that the IDS and cited reference(s) be placed in the application filewrapper.

(Filed after payment of issue fee)

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11/26/2004 ZJUHR1

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Statement Under 37 CFR 1.97(e)

- ☐ Each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement; or
- ☐ No item of information contained in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application, and, to the knowledge of the undersigned, after making reasonable inquiry, no item of information contained in the information disclosure statement was known to any individual designated in 37 CFR 1.56(c) more than three months prior to the filing of this Information Disclosure Statement.

Statement Under 37 CFR 1.704(d) (Patent Term Adjustment)

Applies to original applications (other than design) filed on or after May 29, 2000

- ☐ Each item of information contained in the Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart application and this communication was not received by any individual designated in § 1.56(c) more than thirty days prior to the filing of the Information Disclosure Statement.
- ☒ Enclosed herewith is form PTO-1449:
- ☒ Copies of the cited references are enclosed.
- ☒ Since this application was filed after June 30, 2003, copies of issued U.S. patents and published U.S. applications are not required and are not being provided.
- ☐ Copies of the cited references are enclosed except those entered in prior application, U.S. Application No. [], to which priority under 35 U.S.C. 120 is claimed. [The earlier application contains copies of the cited references.]
- ☐ The listed references were cited in the enclosed International Search Report in a counterpart foreign application.
- ☐ The "concise explanation" requirement (non-English references) for reference(s) [] under 37 CFR 1.98(a)(3) is satisfied by:
- ☐ the explanation provided on the attached sheet.
- ☐ the explanation provided in the Specification.
- ☐ submission of the enclosed International Search Report.
- ☐ submission of the enclosed English-language version of a foreign Search Report and/or foreign Office Action.
- ☐ the enclosed English language abstract.

☐ Applicant requests that the following non-published pending applications be considered:

Examiner's
Initials

_____ U.S. Patent Application No. [], by [inventor(s)], filed [], Docket No.: []

_____ U.S. Patent Application No. [], by [inventor(s)], filed [], Docket No.: []

_____ U.S. Patent Application No. [], by [inventor(s)], filed [], Docket No.: []

Examiner

Date

☐ A copy of each above-cited application, including the current claims, is enclosed.

☐ A copy of each above-cited application, including the current claims, is enclosed, except those entered in prior application, U.S. Application No. [], to which priority under 35 U.S.C. 120 is claimed.

The Examiner is requested to return a copy of the above list of pending applications indicating which references were considered with the next office communication.

It is requested that the information disclosed herein be made of record in this application.

Method of payment:

☒ A check for the fee noted above is enclosed, or the fee has been included in the check with the accompanying Reply. A copy of this Statement is enclosed.

☐ Please charge Deposit Account 08-0380 in the amount of \$[]. A copy of this Statement is enclosed.

☒ Please charge any deficiency in fees and credit any overpayment to Deposit Account 08-0380.

Respectfully submitted,

HAMILTON, BROOK, SMITH & REYNOLDS, P.C.

By 

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Dated: 22 November 2004

PTO-1449 REPRODUCED

ATTORNEY DOCKET NO.
3194.1026-002APPLICATION NO.
10/683,904INFORMATION DISCLOSURE CITATION
IN AN APPLICATIONFIRST NAMED INVENTOR
Daniel Alvarez, Jr.FILING DATE
October 10, 2003

November 11, 2004

EXAMINER
Bibi Sharidan CarrilloCONFIRMATION NO.
3090GROUP
1746

Use several sheets if necessary)

U.S. PATENT DOCUMENTS

EXAM- INER INI- TIAL	REF. NO.	DOCUMENT NUMBER Number-Kind Code (if known)	ISSUE DATE / PUBLICATION DATE MM-DD-YYYY	NAME OF PATENTEE OR APPLICANT OF CITED DOCUMENT
	AA	5,013,335	05-07-1991	Marcus
	AB	5,160,512	11-03-1992	Talu
	AC	5,351,415A	10-04-1994	Brooks <i>et al.</i>
	AD	5,540,757	07-30-1996	Jordan, Sr.
	AE	5,602,683A	02-11-1997	Straaijer <i>et al.</i>
	AF	5,676,737	10-14-1997	Whitlock
	AG	5,883,738A	11-10-1998	Carrea <i>et al.</i>
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	AK	6,221,132 B1	04-24-2001	Dong <i>et al.</i>
	AA2	6,391,090B1	05-21-2002	Alvarez, Jr. <i>et al.</i>
	AB2	6,427,703B1	08-06-2002	Somekh
	AC2	6,461,410	10-08-2002	Abe <i>et al.</i>
	AD2	6,638,341B1	10-28-2003	Speigelman <i>et al.</i>
	AE2	6,724,460B2	04-20-2004	Van Schaik <i>et al.</i>
	AF2	US2002/0018189A1	02-14-2002	Mulkens <i>et al.</i>
	AG2	US2003/0096193A1	05-22-2003	Van Schaik <i>et al.</i>
	AH2	US2002/0192129A1	12-19-2002	Shamouilian <i>et al.</i>

EXAMINER

DATE CONSIDERED

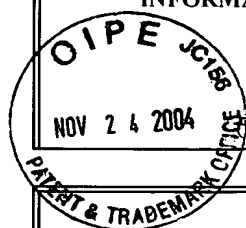
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(Use several sheets if necessary)



OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

AR	Handbook of Semiconductor Wafer Cleaning Technology, Science, Technology, and Applications, Werner Kern Associates, eds., (NJ: Noyes Publications) pp. 88-89 (1993).
AS	Veillerot, Marc, "A Method for Measuring AMC Concentrations Inside Wafer Containers," Materials Integrity Management Symposium 2003.
AT	Martin, Ray <i>et al.</i> , "Status of Microenvironment Gas Purge in the Semiconductor Industry," Materials Integrity Management Symposium 2003.
AU	Davidson, John, "The Expanding Role of Bare Reticle Stockers in Photolithography," Materials Integrity Management Symposium 2003.
AV	Veillerot <i>et al.</i> , "Organic Contamination: Purge Gas Impacts in Plastic Storage Boxes," Solid State Phenomena, vol. 92, pp. 105-108 (2003).
AW	Veillerot <i>et al.</i> , "Testing the use of purge gas in wafer storage and transport containers," [online] 1997-2003 [retrieved 2004-11-10]. Retrieved from the Internet <URL: http://www.micromagazine.com/archive/03/08/veillerot.html >
AX	Pearlstein <i>et al.</i> , "Evaluating electronics-grade gas-line purging requirements," [online] March, 2001 [retrieved 2004-10-18]. Retrieved from the Internet <URL: http://sst.pennnet.com/Articles/Article_Display.cfm?Section=ARCHI&ARTICLE_ID=95491&VERSION_NUM=1&p=5 >

EXAMINER

DATE CONSIDERED